Docket No.: 50432-067

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#13 ps

le Application of

Kai YANG, et al.

Serial No.: 09/817,056

Group Art Unit: 2811

Filed: March 27, 2001

Examiner: T. NGUYEN

For: STABILIZING FLUORINE ETCHING OF LOW-K MATERIALS

## INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed more than three months after the U.S. filing date AND after the mailing date of the first Office Action on the merits, but before the mailing date of a Final Rejection or Notice of Allowance.

## **CERTIFICATION PARAGRAPH**

The undersigned certifies that, to the best of his knowledge, each item of information contained in this Information Disclosure Statement was first cited in a communication from a

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foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement as described in 37 CFR 1.97(e)(1). No fee is required.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

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